In th Claims

CLAIMS

Claims 1-30 (Canceled).

31. (New) An engagement probe formed from a semiconductor material and having a grouping of a plurality of projecting apexes positioned is sufficient proximity to one another to collectively engage a single conductive pad on a semiconductor substrate.

32. (New) The engagement probe of claim 31 comprising a plurality of such groupings for engaging multiple conductive pads on the semiconductor substrate.

33. (New) The engagement probe of claim 31 wherein the apexes are in the shape of multiple knife-edge lines.

34. (New) The engagement probe of claim 31 wherein the apexes are in the shape of multiple knife-edge lines, the multiple knife-edge lines being positioned to form at least one polygon.

35. (New) The engagement probe of claim 31 wherein the apexes are in the shape of multiple knife-edge lines, the multiple knife-edge lines being positioned to form at least two polygons one of which is received entirely within the other.

36. (New) The engagement probe of claim 31 wherein the grouping of apexes is formed on a projection from a substrate.

37. (New) The engagement probe of claim 31 wherein the apexes have a selected projecting distance, the projecting distance being about one-half the thickness of the conductive pad which the apparatus is adapted to engage.

38. (New) The engagement probe of claim 31 wherein the apexes project from a common plane, the apexes having respective tips and bases, the bases of adjacent projecting apexes being spaced from one another to define a penetration stop plane therebetween.

39. (New) The engagement probe of claim 31 wherein the apexes project from a common plane, the apexes having respective tips and bases, the bases of adjacent projecting apexes being spaced from one another to define a penetration stop plane therebetween, the tips being a distance from the penetration stop plane of about one-half the thickness of the conductive pad which the apparatus is adapted to engage.

40. (New) The engagement probe of claim 31 wherein the apexes are in the shape of multiple knife-edge lines, the multiple knife-edge lines interconnecting to form at least one fully enclosed polygon.

41. (New) The engagement probe of claim 31 wherein outermost portions of the electrically conductive apexes constitute a first electrically conductive material, and wherein the conductive pads for which the probe is adapted have outermost portions constituting a second electrically conductive material; the first and second electrically conductive materials being different.